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Application No. 10/658,472 Docket No. 740756-2650

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Hidekazu MIYAIRI et al.

Serial No. 10/658,472

Filed: September 10, 2003

For: LASER APPARATUS, LASER IRRADIATION

METHOD, AND MANUFACTURING METHOD OF

SEMICONDUCTOR DEVICE

D

Examiner: Phillip Nguyen

Group Art Unit: 2828

Forup Art Unit: 2828

CERTIFICATE OF MAILING OR TRANSMISSION

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage for First Class Main in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, or being facsimile transmitted to the USP/O at 571-273-8300, or July 7, 2006.

Signature:

Name: Pamela L. Patrick

INFORMATION DISCLOSURE STATEMENT

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In accordance with the duty of disclosure as set forth in 37 C.F.R. §1.56, Applicants hereby submit the following information in conformance with 37 C.F.R. §§ 1.97 and 1.98. Pursuant to 37 C.F.R. § 1.98, a copy of each of the documents cited is enclosed.

It is requested that the accompanying PTO-1449 be considered and made of record in the above-identified application. To assist the Examiner, the documents are listed on the attached form PTO-1449. It is respectfully requested that an Examiner initial a copy of this form be returned to the undersigned.

The Commissioner is authorized to charge the amount of \$180,00 to Deposit Account No. 19-2380 (740756-2650) in compliance with the provisions of 37 C.F.R. § 1.97(c)

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PAGE 1/15* RCVD AT 7/7/2006 6:20:54 PM [Eastern Daylight Time] * SVR:USPTO-EFXRF-3/9 * DNIS:2738300 * CSID:866 741 0075 * DURATION (mm-ss):04-52

ils Patent Page 3/15 and 5/15

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Application No. 10/658,472, Docket No. 740756-2650

The Commissioner is hereby authorized to charge any fees connected with this filing which may be required now, or credit any overpayment to Deposit Account No. 19-2380.

Respectfully submitted,

Βv

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Substitute for form 1449A/PTO				Complete if Known		
INFORMATION DISCLOSURE				Application Number	10/658,472	
STATEMENT BY APPLICANT (use as many shoets as necessary)				Filing Date	September 10, 2003	
				First Named Inventor	Hideakazu MIYAJRI et al.	
			isary)	Art Unit	2828	
				Examiner Name	Philip Nguyen	
Sheet	1	of	1	Attorney Docket Number	740756-2650	

U.S. PATENT DOCUMENTS							
Examiner Initials	Cito No.1	U.S. Parcai Document	Publication Date	Name of Palcates or	Pages, Cohumps, Lines, Where		
		Number - Kind Code ¹ (if known)	MA-DD-YYYY	Applicant of Cited Document	Relevant Passages or Relevant Figures Appear		
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_		OTHER PRIOR A	RT – NON PATENT L	WERATURE DOCUMENT	rs				
Examiner Initials	Cite No.1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriats), title of the item (book, magnzine, journal, acrial, symposium, catalog, etc.)., date, page(s), volume-issue number(s), publisher, city and/or country where published.							
		Hideaki KUSAMA, "EXCIMER LASER ANNEALING APPARATUS", Liquid Crystal Display Technology 2001, Liquid Crystal Display Manufacturing Technology Edition, pp. 138-141; July 1, 2001. (Japanese Article with Full Translation)							
Examiner				Date Considered		<u> </u>			

^{*}EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Applicant's unique citation designation number (optional). ² See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. ¹ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. Skind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. Applicant is to place a check mark here if English language Translation is attached.

¹ Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.